CLAIMS

- 1. Method for producing a superconducting inductive component having at least two plots, this component comprising at least one line segment incorporating at least one plot of the component, this line segment constituting a conducting or superconducting layer within a stack (E) of alternately superconducting (CI) and insulating (C2) films.
- 2. Method according to claim 1, characterized in that each film constituting the stack (E) is perfectly crystallized.
 - 3. Method according to one of claims 1 or 2, characterized in that it comprises a prior step of depositing an insulating film (C2) on a substrate (S).

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- 4. Method according to one of claims 1 or 2, characterized in that it comprises a prior step of depositing a superconducting film (CI) on a substrate (S).
- 5. Method according to one of claims 1 or 2, characterized in that it comprises a prior step of depositing a superconducting film (L1) on a substrate (S) followed by the depositing of the stack (E).
- 6. Method according to one of claims 3 or 4, characterized in that it comprises moreover the following steps:
 - a deposit of the stack (E) of alternately superconducting (Cl) and insulating (C2) films,
 - an etching of the stack (E) carried out in such a way that the latter only remains at the locations where an inductive component is to be implanted.

- 7. Method according to claim 5, characterized in that it comprises moreover the following steps:
- an etching of the stack (E) carried out in such a way that the latter only remains at the locations where an inductive component is to be implanted.
 - an etching of the superconducting film (L1).
- 8. Method according to claim 5, characterized in that it comprises moreover the following steps:
- a simultaneous etching of the stack (E) and of the superconducting film (L1)
- an etching of the stack (E) carried out in such a way that the latter only remains at the locations where an inductive component is to be implanted.

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- 9. Method according to one of the preceding claims, characterized in that at least one of the superconducting films (CI) is produced from $YB_{a2}Cu_3O_{7-\delta}$ compounds.
- 10. Method according to one of the preceding claims, characterized in that at least one of the insulating films (C2) is made from $LaA10_3$ compounds.
- 11. System for producing a superconducting inductive 25 component having at least two plots, this component comprising at least one line segment incorporating at least one plot of the component, this line segment constituting a conducting or superconducting layer within a stack (E) of alternately superconducting (CI) and insulating (C2) films, implementing the method according to one of the preceding claims. 30

- 12. System according to claim 11, characterized in that it comprises:
- means for depositing a stack (E) of alternately superconducting and insulating films, and
- means for etching all of the deposited films, these means being arranged in such a way that said deposited films remain only at the locations where an inductive component is to be implanted.
- 13. System according to claim 11, characterized in that it comprises:
 - means for depositing a superconducting film (LI) on a substrate (S),
 - means for depositing on the superconducting film (L1) a stack (E) of alternately superconducting and insulating films, and
 - means for etching all of the deposited films, these means being arranged in such a way that the film (L1) remains only at the locations where a superconducting line is to be implanted and the stack (E) remains only at the locations where an inductive component is to be implanted.

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- 14. Antenna device comprising an electronic circuit including a superconducting inductive component produced by the method according to one of claims 1 to 10.
- 15. Antenna device according to claim 14, characterized in that the antenna is produced from a superconducting thin film.
- 16. Delay line device comprising an inductive component in serie and a capacitive component in parallel downstream of said inductive component, characterized in that the inductive component is a superconducting inductive component produced by the method according to one of claims 1 to 10.

17. Phase shift radar device comprising a plurality of antennas each comprising an electronic circuit including a delay line according to claim 16, this delay line being arranged such that each of said antennas transmits a signal whose phase is shifted with respect to that of the near antennas.

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- 18. Electronic frequency filtering device comprising an electronic circuit including a superconducting inductive component produced by the method according to one of claims 1 to 10.
- 19. High-pass filter device comprising an inductive component in parallel and a capacitive component in serie downstream of said inductive component, characterized in that the inductive component is a superconducting inductive component produced by the method according to one of claims 1 to 10.
- 20. Low-pass filter device comprising a capacitive component in parallel and an inductive component in serie downstream of said capacitive component, characterized in that the inductive component is a superconducting inductive component produced by the method according to one of claims 1 to 10.